Filing Date: September 29, 2003

Title: DIFFUSION BARRIER LAYER FOR LEAD FREE PACKAGE SUBSTRATE

Assignee: Intel Corporation

IN THE CLAIMS

Please amend the claims as follows:

- 1. (Currently Amended) A ball grid array device comprising:
- a substrate, further including:
 - a first major surface; and
 - a second major surface; and

an array of pads made of an electrically conductive material, the array of pads positioned on the first major surface; and

a solder ball formed on at least one of the array of pads, at least one of the array of pads including a solderable diffusion retarding layer for controlling the out-diffusion of the electrically conductive material from the at least one pad to the solder ball during a solder reflow process.

- 2. (Original) The ball grid array device of claim 1 further comprising a binding layer for binding the diffusion retarding layer to the conductive material of the at least one pad.
- 3. (Original) The ball grid array device of claim 2 further comprising a layer of material for receiving solder.
- 4. (Original) The ball grid array device of claim 2 further comprising a layer of material for receiving solder placed on the diffusion retarding layer.
- 5. (Original) The ball grid array device of claim 1 wherein the electrically conductive of the pad includes copper.
 - 6. (Canceled)
- 7. (Original) The ball grid array device of claim 1 wherein the diffusion retarding layer includes 54Fe-29Ni-17Co.

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8. (Original) The ball grid array device of claim 2 wherein the binding layer includes Titanium (Ti).

- 9. (Original) The ball grid array device of claim 2 wherein the binding layer is Titanium (Ti).
- 10. (Original) The ball grid array device of claim 9 wherein the Titanium binding layer has a thickness in the range of 80 nanometers (nm) to 120 nanometers (nm).
- 11. (Original) The ball grid array device of claim 9 wherein the Titanium binding layer has a thickness in the range of 90 nanometers (nm) to 110 nanometers (nm).
- 12. (Original) The ball grid array device of claim 4 wherein the layer of material for receiving solder includes gold (Au).
- 13. (Original) The ball grid array device of claim 4 wherein the layer of material for receiving solder is gold (Au).
 - 14. (Currently Amended) A substrate comprising:
 - at least one pad of a copper material;
 - a diffusion retarding layer placed over the at least one pad; and
- a layer of gold over the at least one pad diffusion retarding layer, wherein the diffusion layer is adapted to control the out-diffusion of copper material from the at least one pad.
- 15. (Original) The substrate of claim 14 wherein the diffusion retarding layer includes 54Fe-29Ni-17Co.
- 16. (Original) The substrate of claim 14 further comprising a layer of titanium (Ti) used to bond the diffusion retarding layer to the material of the at least one pad.

AMENDMENT AND RESPONSE UNDER 37 CFR § 1.111

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17. (Original) The substrate of claim 14 wherein the diffusion retarding layer includes 54Fe-29Ni-17Co, the substrate further comprising a layer of titanium (Ti) used to bond the diffusion retarding layer to the material of the at least one pad.

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- 18. (Original) The substrate of claim 14 further comprising a plurality of pads.
- 19. (Original) The substrate of claim 14 further comprising a plurality of pads arranged in an array.
 - 20. 27. (Canceled)
 - 28. (Previously Presented) A ball grid array device comprising:

a substrate including a first major surface, the substrate further including an array of pads made of an electrically conductive material, the array of pads positioned on the first major surface;

a diffusion retarding layer placed on at least one of the array of pads; and solder placed on at least one of the array of pads, the solder and the pad including a intermetallic compound including Ni-Sn (Ni₃Sn₄) and Sn-Fe.

- 29. (Original) The ball grid array device of claim 28 wherein the solder is lead-free.
- 30. (Original) The ball grid array device of claim 28 wherein the pad includes a layer of gold.
 - 31. (Previously Presented) An electronic device comprising:
 - a copper pad on the electronic device; and

means to retard diffusion of the copper associated with the copper pad adapted to retard the out-diffusion of the copper from the pad during a solder reflow process.

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32. (Previously Presented) The electronic device of claim 31 wherein the means to retard diffusion of the copper includes a layer of binding material.

- 33. (Previously Presented) The electronic device of claim 31 further comprising a layer of solderability enhancing material attached to the means to retard diffusion.
 - 34. (Previously Presented) The electronic device of claim 31 further comprising means for binding the pad and the means to retard diffusion; and a solderable layer of material attached to the copper pad.
 - 35. (Currently Amended) A ball grid array device comprising:
 - a substrate;
 - a copper pad on the substrate;
 - means to retard <u>out-diffusion</u> of the copper associated with the copper pad; and a solder ball attached to the copper pad.
- 36. (Previously Presented) The ball grid array device of claim 35 wherein the solder ball is formed from a lead free material.
- 37. (Previously Presented) The ball grid array device of claim 35 further comprising a binder for attaching the means to retard copper to the copper pad.
- 38. (Previously Presented) The ball grid array device of claim 37 wherein the binder includes a layer of titanium (Ti) on the copper pad.
- 39. (Previously Presented) The ball grid array device of claim 35 further comprising a layer of gold associated with the means to retard diffusion of copper.
 - 40. (Canceled)